

10077072
02/14/02

PATENT NUMBER and
ISSUE DATE

U.S. UTILITY Patent Application

APPLICATION

APPL NUM	FILING DATE	CLASS	SUBCLASS	GAU	EXAMINER
10077072	02/14/2002	315	111.21	287	<i>ll</i>

**APPLICANTS: Fischer Andreas; Trussell Dave; Kennedy Bill; Loewenhardt Peter;

**CONTINUING DATA VERIFIED:

None N/A

BEST AVAILABLE C...

** FOREIGN APPLICATIONS VERIFIED:

None N/A

PG-PUB DO NOT PUBLISH

RESCIND

ATTORNEY DOCKET NO

Foreign priority claimed

yes no

35 USC 119 conditions met

yes no

Verified and Acknowledged Examiners initials *MRA*

P0877

TITLE : Plasma processing apparatus and method for confining an RF plasma under very high gas flow
and RF power Density conditions

U.S. DEPT. OF COMM /PAT. & TM-PTO 425L (Rev. 12-94)

NOTICE OF ALLOWANCE MAILED		Assistant Examiner	CLAIMS ALLOWED	
			Total Claims	Print Claim for O.G.
ISSUE FEE		DRAWING		
Amount Due	Date Paid	Sheets Drwg.	Figs.Drwg.	Print Fig.
TERMINAL DISCLAIMER		Primary Examiner		Application Examiner
<input type="checkbox"/>		PREPARED FOR ISSUE		
WARNING: The information disclosed herein may be restricted. Unauthorized disclosure may be prohibited by the United States Code Title 35, Sections 122, 181 and 368, Possession outside the U.S. Patent & Trademark Office is restricted to authorized employees and contractors only.				

FILED WITH:

DISK (CRF)

CD-ROM

(Attached in pocket on right inside flap)